

IN THE CLAIMS

Please amend Claims 1 and 9 as follows:

1. (Previously Presented) A device for the inspection of surfaces (10) of one or more semiconductors (14), comprising:
  - at least one laser light source (1);
  - a detector (28) for detecting an intensity of light (13) that is reflected by the surface (10) to be inspected; and
  - at least one mode filter (15; 15.1) between the surface (10) and the detector (28).
2. (Previously Presented) A device according to claim 1, wherein the mode filter (15; 15.1) suppresses a mode in the reflected light (13) that corresponds to a mode of the laser light source (1).
3. (Previously Presented) A device according to claim 1, wherein the mode filter comprises a beam splitter (21) which splits a light beam (13) into at least two sub-beams (13.2; 13.3) that interfere with one another.
4. (Previously Presented) A device according to claim 3, wherein the mode filter includes a device (22) for mode-selective phase

shifting and one of the sub-beams (13.3) traverses the device (22) for mode-selective phase shifting.

5. (Previously Presented) A device according to claim 4, wherein the device (22) effects a phase shift of a mode through  $180^\circ$  overall, together with a difference in path length, so that the sub-beams (13.2; 13.3) interfere destructively in respect of this mode.

6. (Previously Presented) A device according to claim 5, wherein the device (22) includes a lens system (26; 27) that operates on a Guoy phase system basis so as to effect the phase shift through  $180^\circ$ .

7-8 (Cancelled)

9. (Previously Presented) A method for the inspection of a surface of one or more semiconductors, comprising the steps of:

irradiating said surface by means of at least one laser light source; and

detecting an intensity of light that is reflected by the surface to be inspected in at least one detector, wherein the laser light source emits light of a defined mode and that light that is

reflected by the surface is guided through a mode filter.

10. (Previously Presented) A method according to claim 9, wherein the mode filter suppresses the mode of the laser light source and no signal is detected where reflection does not affect the mode.